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Docket No. F-6971

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Seiichi HAYASHI, et al.  
Serial No. : 09/852,111  
Filed : May 9, 2001  
For : METHOD AND APPARATUS FOR MEASURING THIN FILM, AND THIN FILM DEPOSITION SYSTEM  
Group Art Unit : 2882  
Examiner : Hoon K. Song  
Confirmation No. : 5010  
Customer No. : 000028107

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Commissioner for Patents  
P.O. Box 1450  
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AMENDMENT

04/08/2004 WABRHAM1 00000110 101250 09852111  
01 FC:1253 950.00 DA

**INTRODUCTORY COMMENTS:**

Sir:

In response to the Office Action of October 3, 2003, please amend the above-identified patent application as follows: